

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 10/553,573
Applicants: Christian DUSSARRAT et al.
Filed Internationally: April 8, 2004
US National: October 17, 2005
Title: METHODS FOR PRODUCING SILICON NITRIDE FILMS
BY VAPOR-PHASE GROWTH
TC/A.U.: 1715
Examiner: Elizabeth A. Burkhardt
Docket No.: Serie 6070
Customer No.: 40582

INFORMATION DISCLOSURE STATEMENT

Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

In accordance with the duty of disclosure as set forth in 37 C.F.R. § 1.56, Applicants hereby submit the following information in conformance with 37 C.F.R. §§ 1.97 and 1.98. Pursuant to 37 C.F.R. § 1.98, a copy of each of the non-US patent documents cited on the attached PTO Form 1449 is enclosed. It is respectfully requested that an Examiner-initialed copy of this form be returned to the undersigned.

Pursuant to 37 CFR §§ 1.17(p) and 1.97(c)(2), the commissioner is hereby authorized to charge Deposit Account No. 01-1375 in the amount of **\$180.00**. To assist the Examiner, the documents are listed on the attached form PTO-1449. It is respectfully requested that an Examiner-initialed copy of this form be returned to the undersigned.

Respectfully submitted,



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Date: January 28, 2011

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